

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**

<b>Attorney Docket Number</b>	4641-61273
<b>Application Number</b>	10/000,458
<b>Filing Date</b>	November 30, 2001
<b>First Named Inventor</b>	Yahiro
<b>Art Unit</b>	2881
<b>Examiner Name</b>	Mary A. El Shammaa

**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
ME		6,059,981	9-May-2000	Nakasuji
ME		5,396,077	7-Mar-1995	Sohda et al.

**FOREIGN PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
ME		P2001-203149A	27-Jul-2001	Japan

**OTHER DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	
ME		"New imaging and deflection concept for probe-forming microfabrication systems", by H.C. Pfeiffer, J. Vac. Sci, Technol., Vol 12, No. 8, Nov./Dec. 1975, pages 1170-1173

EXAMINER  
SIGNATURE: ME El-Shammaa

DATE  
CONSIDERED: 11.12.03

\* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.